**Sputtered PdO-Doped TiO2 Sensing Layer for a Hydrogen Gas Sensor**

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Figure S1. (a) IR measurement set-up and (b) measured temperature by IR camera as function of applied voltage. From three different heater widths data, we used 60 µm width pattern for MEMS H2 sensor.

Figure S2. Hydrogen gas detection without PdO layer. The hydrogen sensing had 3.5 V applied.